

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. 00862.023131.	APPLICATION NO. 10/615,955		
Date Submitted to PTO:[DATE] <i>SEP 03 2003</i>			APPLICANT HARUHITO ONO ET AL.			
			FILING DATE JULY 10, 2003	GROUP 2874 -NYA		
U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>JDL</i>	T. Sasaki, <i>A Multibeam Scheme for Electron-Beam Lithography</i> , J. Vac. Sci. Technol., 19(4), Nov./Dec. 1981, pp. 963-965					
<i>JDL</i>	K.Y. Lee et al., <i>High Aspect Ratio Aligned Multilayer Microstructure Fabrication</i> , J. Vac. Sci. Technol. B 12(6), Nov/Dec 1994, pp. 3425-3431					
<i>JDL</i>	A.D. Feinerman, et al., <i>Sub-centimeter Micromachined Electron Microscope</i> , J. Vac. Sci. Technol. A 10(4), July/Aug 1992, pp 611-616					
EXAMINER	<i>John D. Lee</i>		DATE CONSIDERED 27 APRIL 2005			

*EXAMINER Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.